App #:   10-807187

EAST SEARCH HISTORY

Databases: US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB

Ref#	Hits	Search Text
S2	2	(("6,538,249") or ("6,456,899")).PN.
S3	1032	((determin$2 or find$3 or detect$3) near ($3focus$3)) and image and (semiconductor or wafer) and correlation
S4	208	S3 and ((determin$2 or find$3 or detect$3) near (edge))
S5	92	S4 and @pd<"20040324"
S6	92	S5 and (distances or depths or heights)
S7	13	("3829691" | "4698503" | "4733074" | "4894540" | "4941980" | "5130540" | "5142147" | "5512747" | "5523568" | "5608218" | "6067164" | "6172365" | "6278114").PN.
S8	7	S7 and edge
S9	6	S8 and predetermined
S10	6	("5544256" | "5943437" | "6259960" | "6288782" | "6292582" | "6314379").PN.
S11	1	10/807187
S12	676	$3focus$3 and image and (semiconductor or wafer) and correlation and edge and "electron microscope" and (wafer or semiconductor) and (distances or depths or heights)
S13	151	S12 and ((determin$2 or find$3 or detect$3) near (edge))
S14	68	S13 and @pd<"20040324"
S15	40	S14 and defects
S16	29	S15 and predetermined
S17	74	("4111557" | "4247203" | "4333838" | "4347001" | "4448532" | "4455485" | "4532650" | "4549204" | "4555798" | "4556317" | "4579455" | "4604910" | "4618938" | "4633504" | "4639587" | "4644172" | "4758094" | "4786170" | "4805123" | "4818110" | "4845373" | "4845558" | "4877326" | "4926489" | "4957367" | "5030008" | "5032735" | "5112129" | "5129010" | "5243406" | "5280542" | "5355212" | "5438413" | "5438417" | "5448364" | "5465145" | "5502306" | "5537669" | "5563702" | "5572598" | "5578821" | "5583632" | "5621532" | "5627646" | "5671056" | "5680207" | "H001530" | "Re34214").PN. OR ("5923430").URPN.
S18	34	S17 and edge
S19	27	S18 and defect
S20	1	((determin$2 or find$3 or detect$3) near ("in focus")) and (distances or depths or heights) and edge and predetermined and image and (semiconductor or wafer) and "electron microscope"
S21	1	((determin$2 or find$3 or detect$3) near ("in focus")) and (distances or depths or heights) and edge and image and (semiconductor or wafer) and "electron microscope"
S22	48	((determin$2 or find$3 or detect$3) near ("in focus")) and (distances or depths or heights) and edge and image and (semiconductor or wafer)
S23	7	((determin$2 or find$3 or detect$3) near ("in focus")) and (distances or depths or heights) and edge and image and (semiconductor or wafer) and defect
S24	24	((determin$2 or find$3 or detect$3) near ("in-focus")) and (distances or depths or heights) and edge and image and (semiconductor or wafer) and defect
S25	15	("4894540").URPN.